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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Examiner: A. Stevenson Shigeyuki UZAWA Group Art Unit: 2812 Application No.: 09/865,454 Confirmation No.: 3754 Filed: May 29, 2001 Allowed: October 22, 2003 For: EXPOSURE APPARATUS, DEVICE MANUFACTURING METHOD, November 5, 2003 SEMICONDUCTOR MANUFACTURING PLANT AND METHOD OF MAINTAINING EXPOSURE APPARATUS

Mail Stop Issue Fee

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

REQUEST FOR CORRECTED NOTICE OF ALLOWANCE

Sir:

Applicant has received a Notice of Allowance and a Notice of Allowability dated October 22, 2003, in the above-identified application, in which the Notice of Allowance lists the TITLE OF INVENTION as "EXPOSURE APPARATUS, DEVICE MANUFACTURING METHOD, SEMICONDUCTOR MANUFACTURING PLANT AND METHOD MAINTAINING EXPOSURE APPARATUS."

The title omits the word "OF" after the word "MAINTAINING." Applicant, therefore, requests that the TITLE OF THE INVENTION be corrected to read -- EXPOSURE APPARATUS, DEVICE MANUFACTURING METHOD, SEMICONDUCTOR

MANUFACTURING PLANT AND METHOD OF MAINTAINING EXPOSURE

APPARATUS --. Accordingly, Applicant requests that a corrected Notice of Allowance be

issued to make this correction.

Applicant believes that no fees should be incurred in connection with filing this paper.

Nevertheless, the Commissioner is authorized to charge Deposit Account No. 06-1205 should

any fees be associated therewith. A duplicate of this document is enclosed for this purpose.

Applicant's undersigned attorney may be reached in our Washington, D.C. office by

telephone at (202) 530-1010. All correspondence should be directed to our below-listed address.

Respectfully submitted,

Attorney for Applicant

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